

**Łukasiewicz**

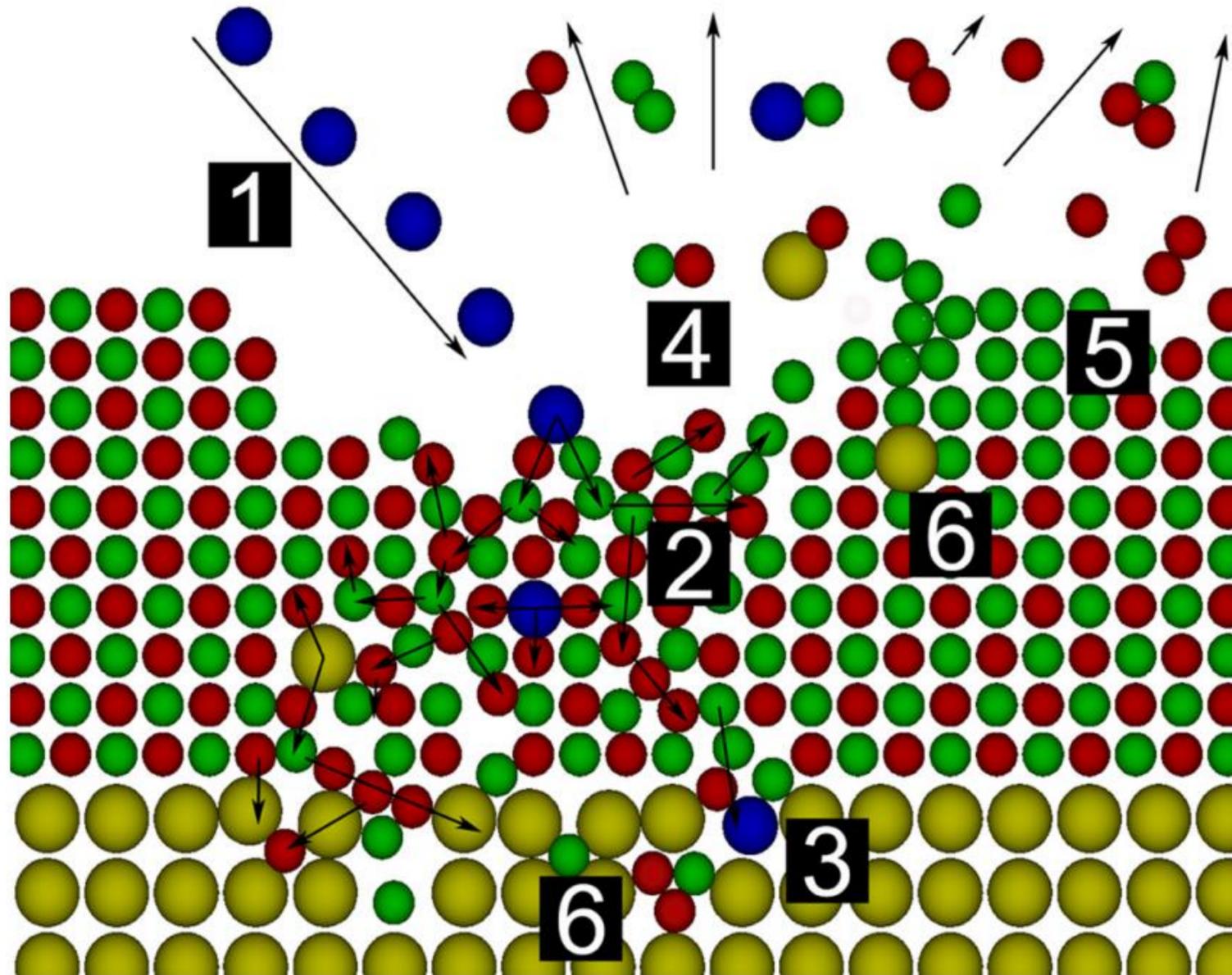
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# **Ultra Low Energy SIMS Depth Profiling of 2D Materials**

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# SIMS - principles



1. Primary beam
2. Collision cascade
3. Implantation
4. Sputtering and ionization
5. Preferential sputtering
6. Mixing

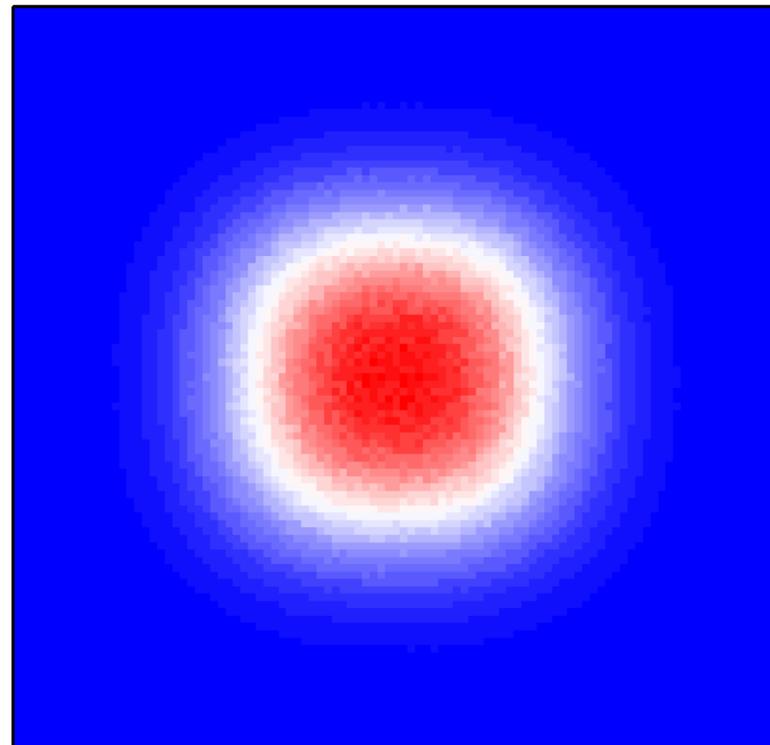
# CAMECA IMS SC Ultra

## EXLIE (EXtreme Low Impact Energy) technology

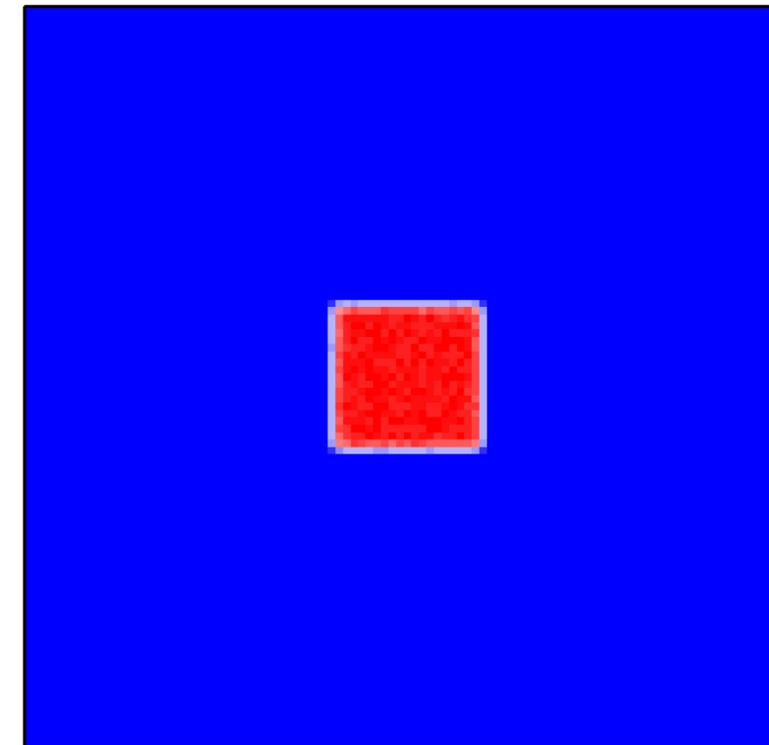
- RF Plasma for oxygen column – down to 60 eV
- Floating voltage for cesium column – down to 90 eV

## Beam shape

Typical Gaussian-shaped beam



Projected on square stencil

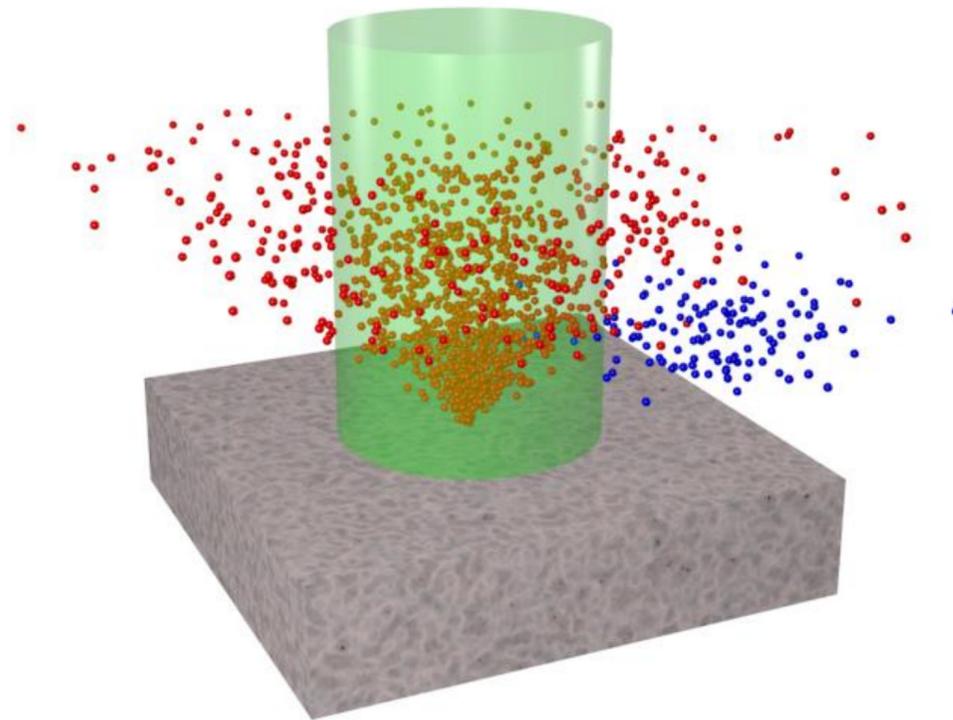


# Dedicated measurement procedures

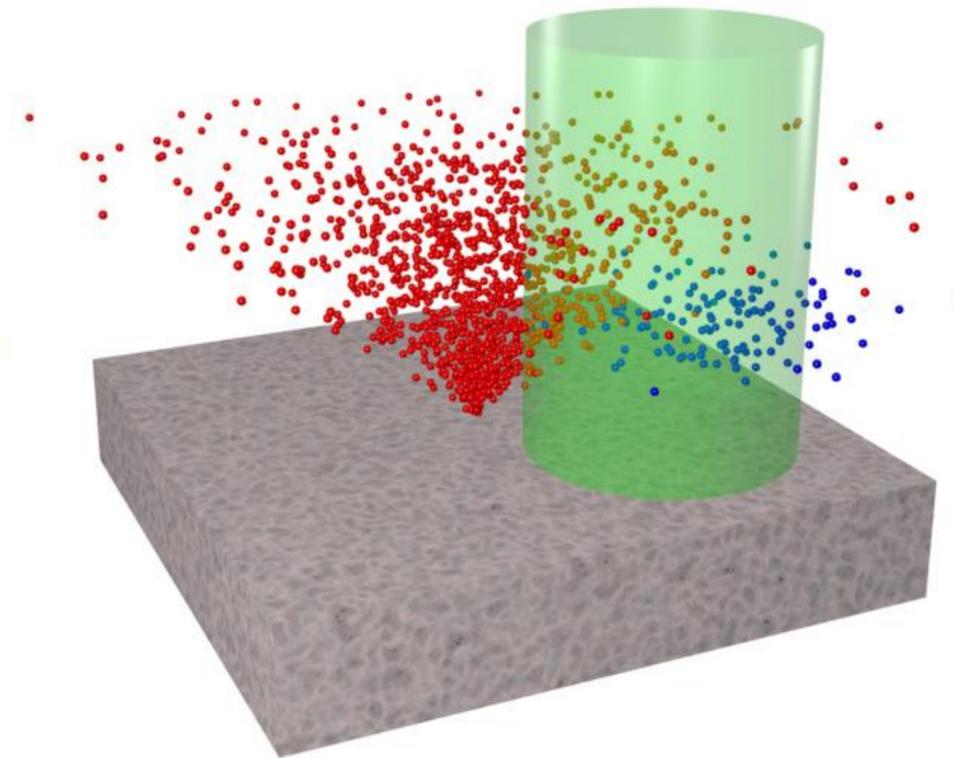
## Type of procedures

- Standard/universal
- Dedicated

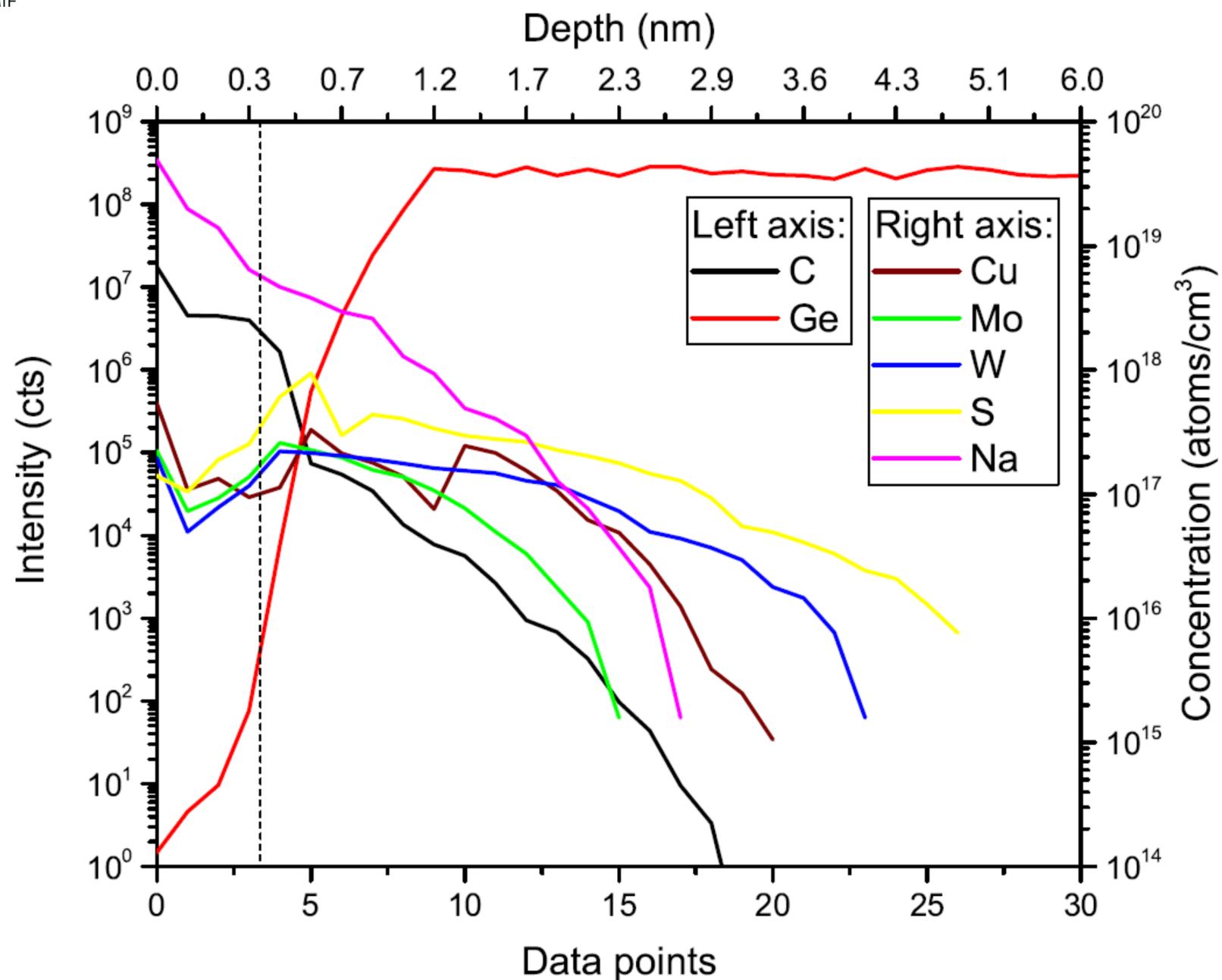
Standard



Dedicated



# How clean is Graphene?



## Remarks

- 250 eV impact energy
- 45° incident angle
- Detection
- Localization?

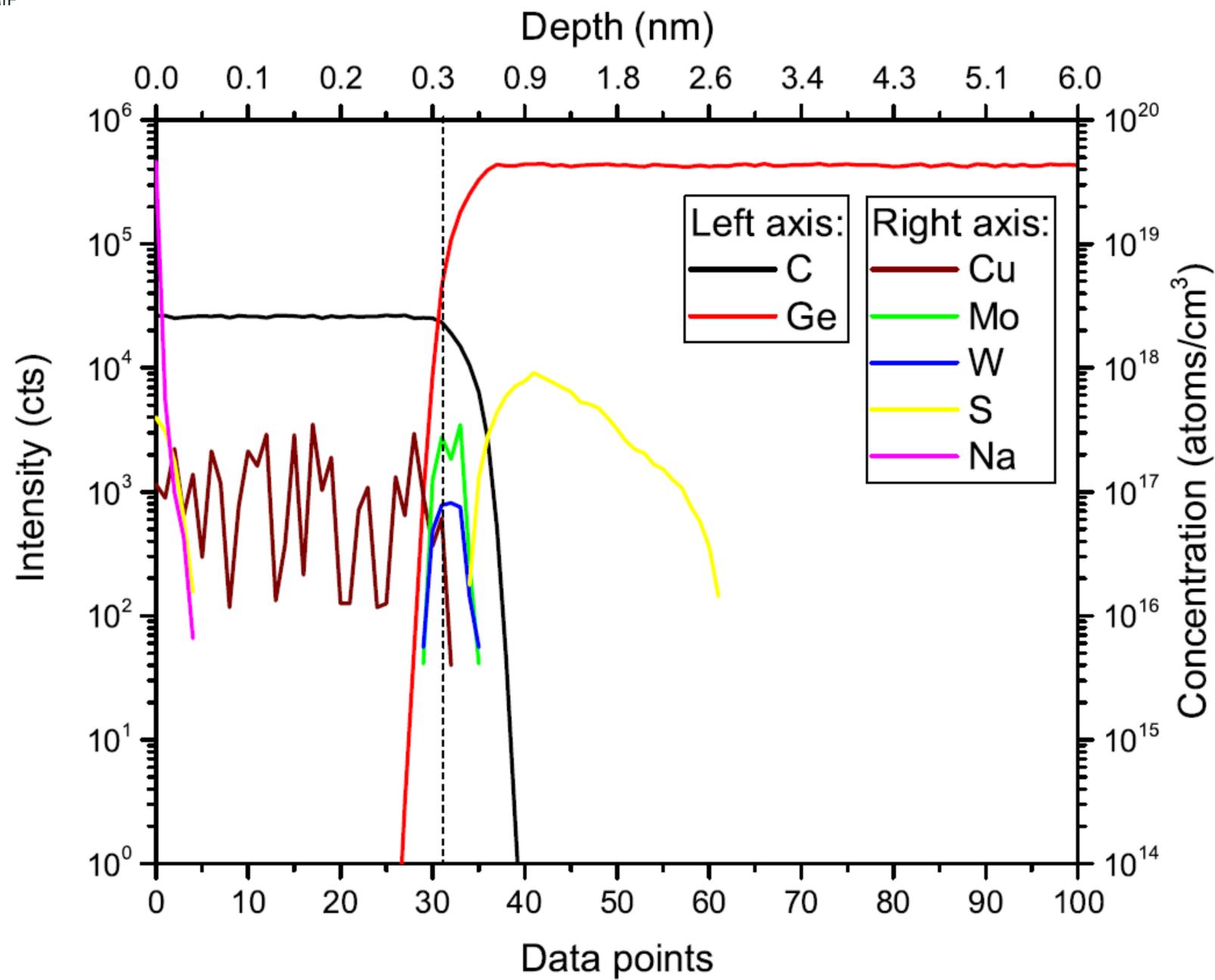
## PROBLEMS AND POTENTIAL SOLUTIONS

Problem	Potential solution	Resulting problems	Potential solution	Conclusion
Transition layer	Lower beam density	Signals intensity reduction	Higher integration time	Still a few data points per graphene
Ion mixing	Lower impact energy	Signals intensity reduction	Higher integration time	Still a few data points per graphene
Preferential sputtering	Higher impact energy	Bigger ion mixing	?	Not feasible

## REALISTIC SOLUTION – HIGH INCIDENT ANGEL

Angle	Data points	Transition layer	Ion mixing	Preferential sputtering	Acquisition time	Detection limits (ppm)
45°	4 for graphene	Severe	Severe	Severe	5 minutes	0.2 – 1.5
75°	30 for graphene	Negligible	Negligible	Negligible	3 hours	0.8 – 2.9

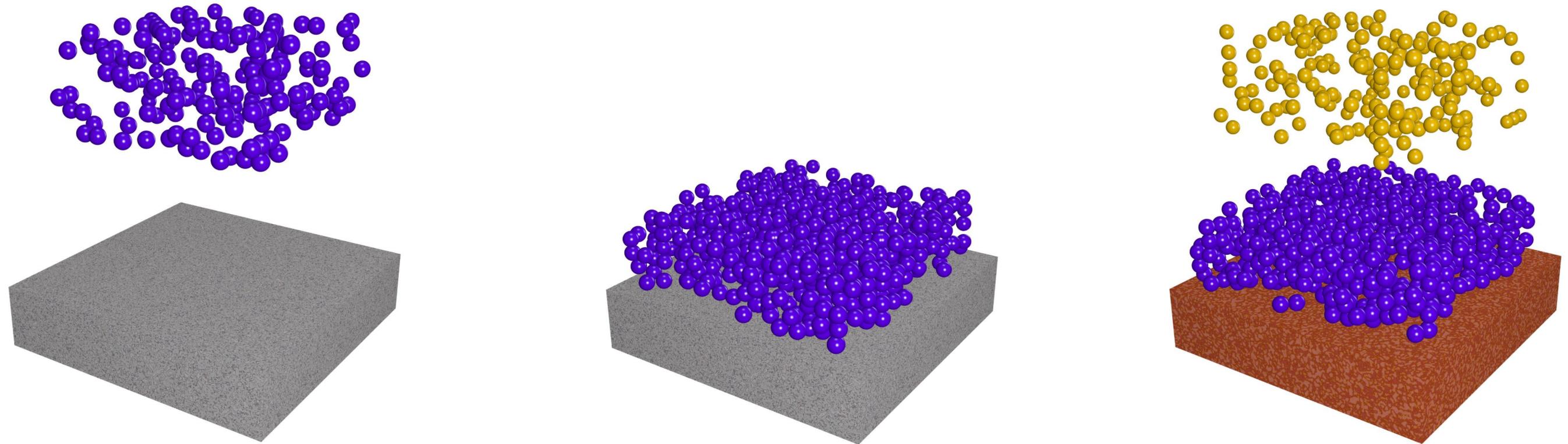
# Enhanced procedure



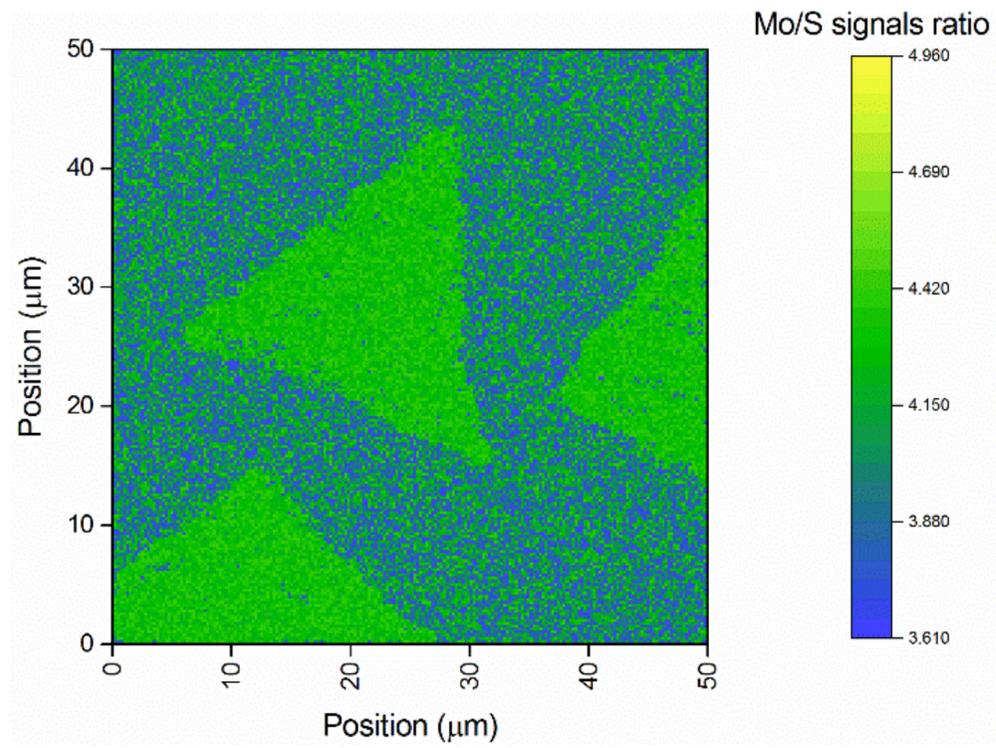
## Remarks

- 250 eV impact energy
- 75° incident angle
- Detection
- Localization!

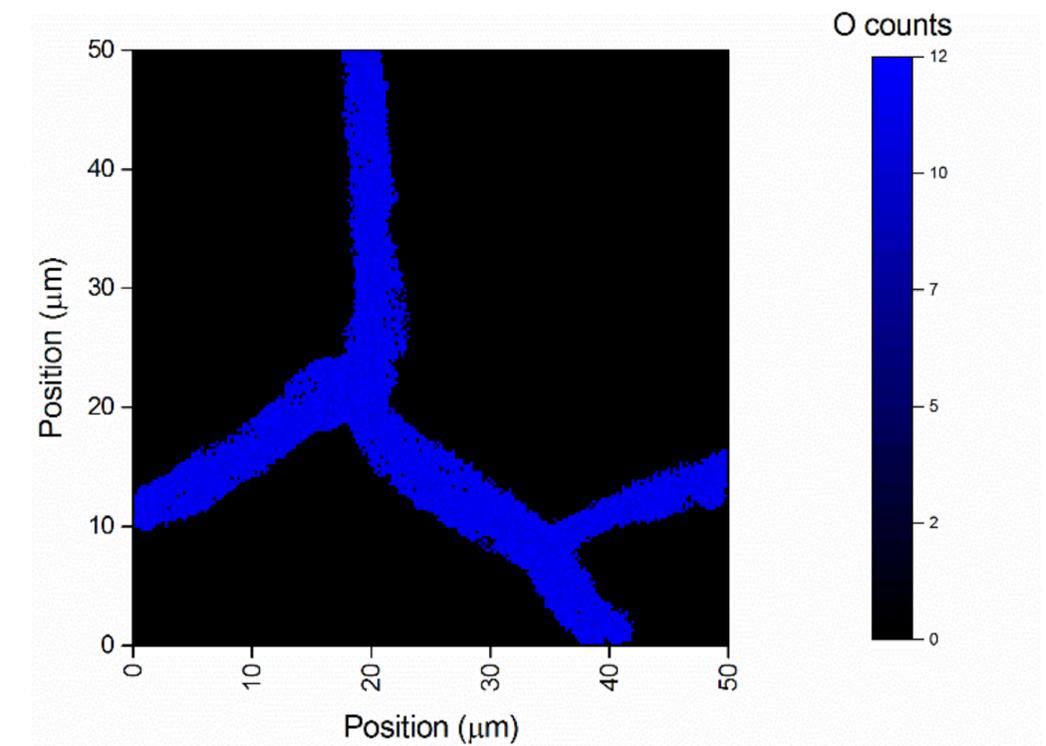
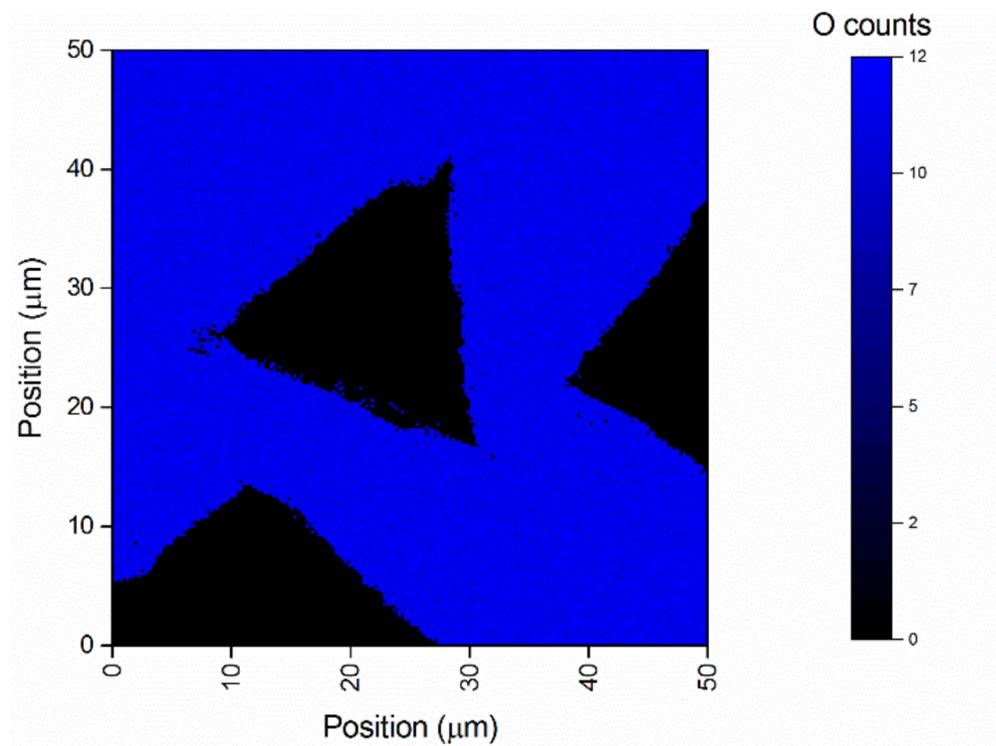
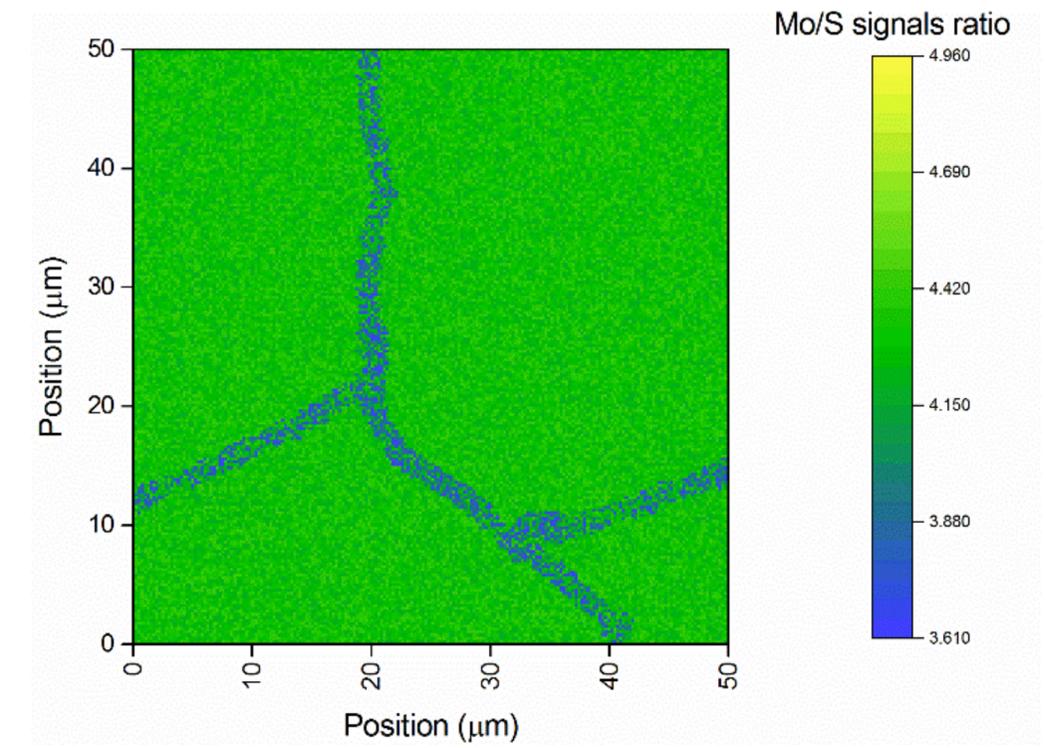
# Molybdenum disulfide



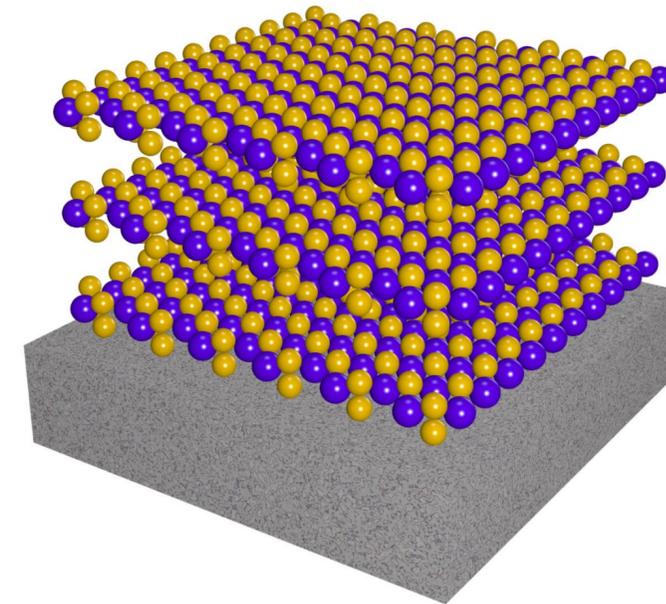
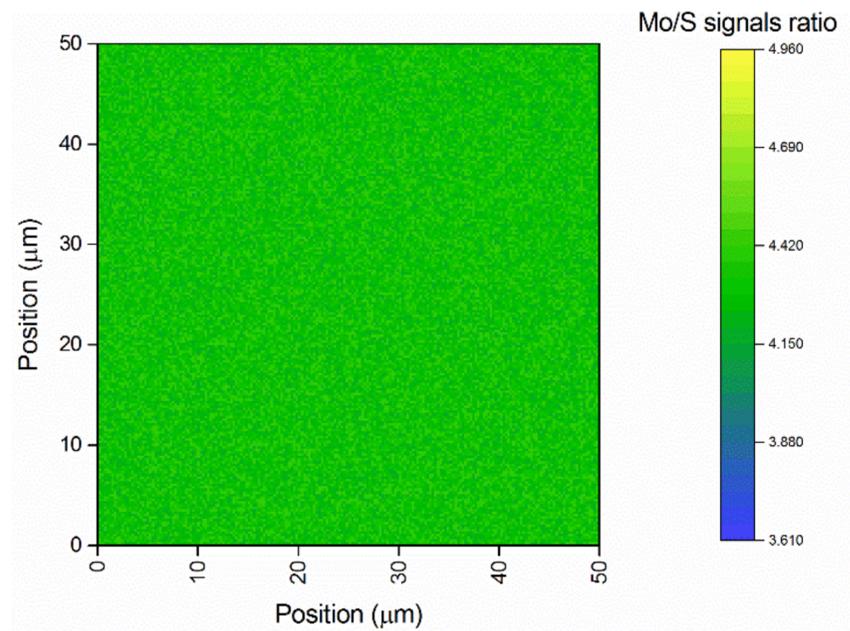
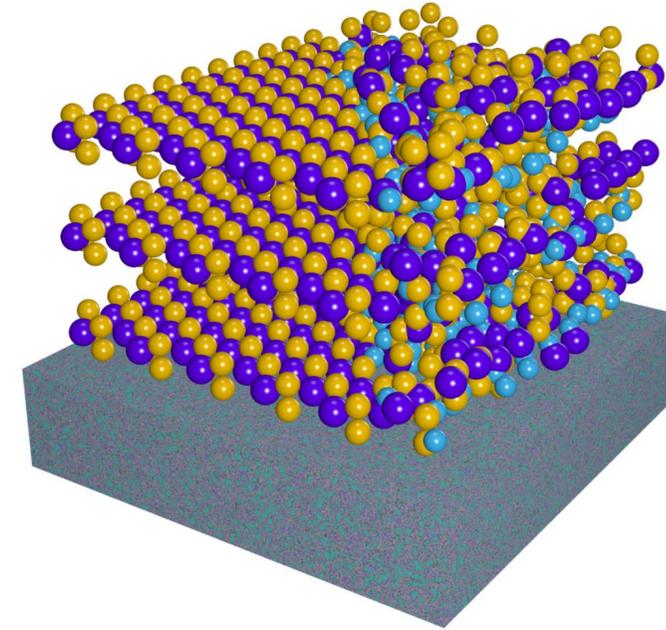
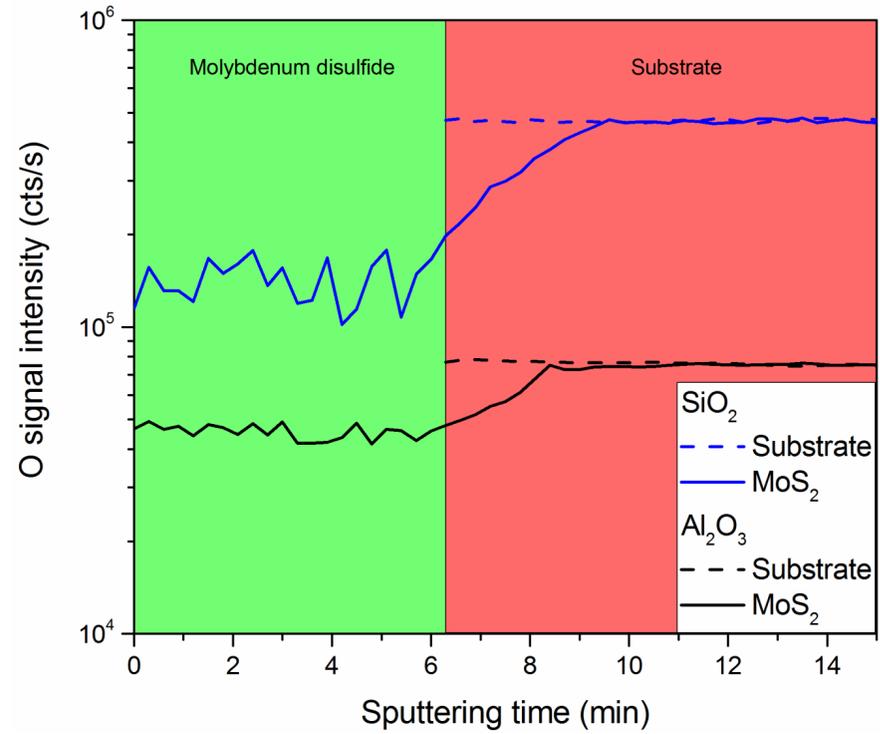
$\text{SiO}_2$



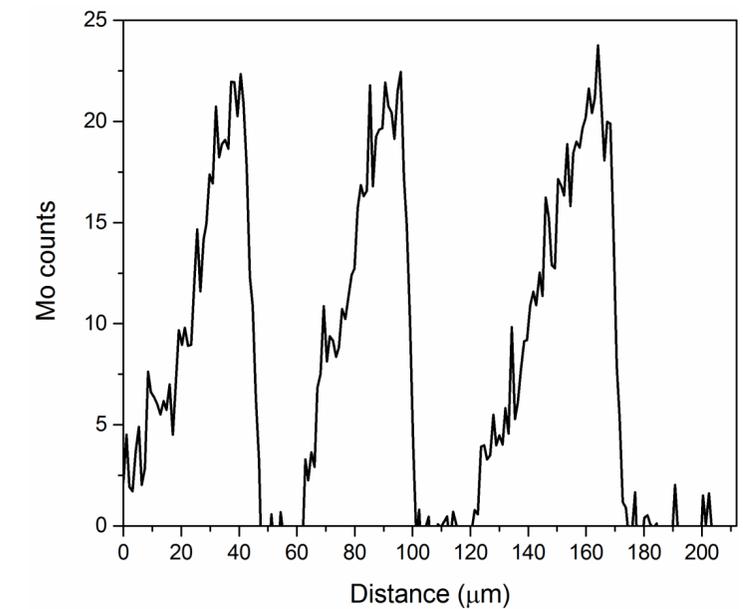
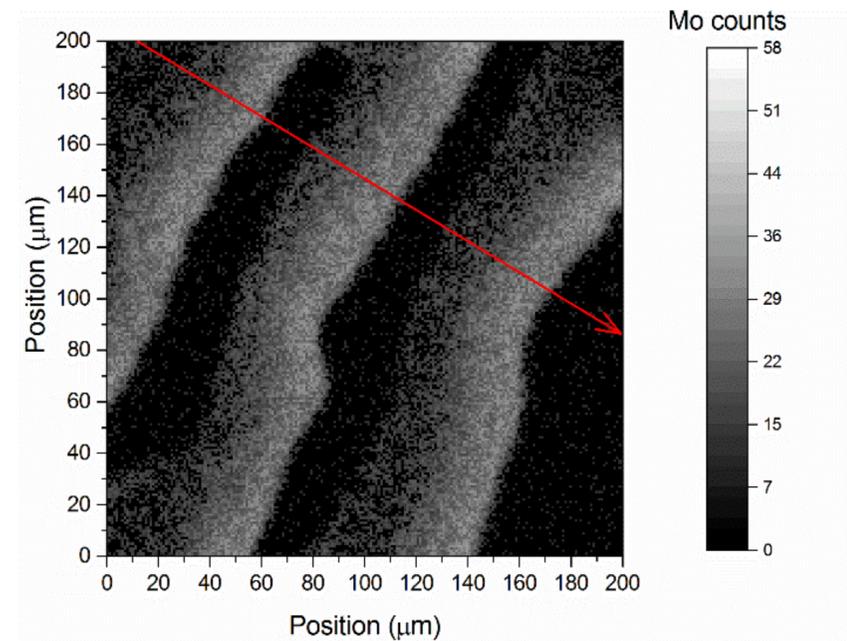
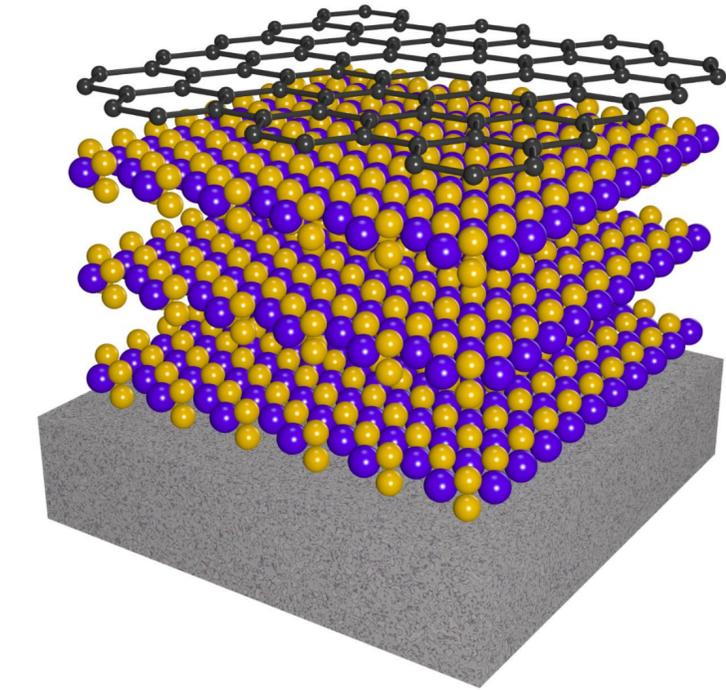
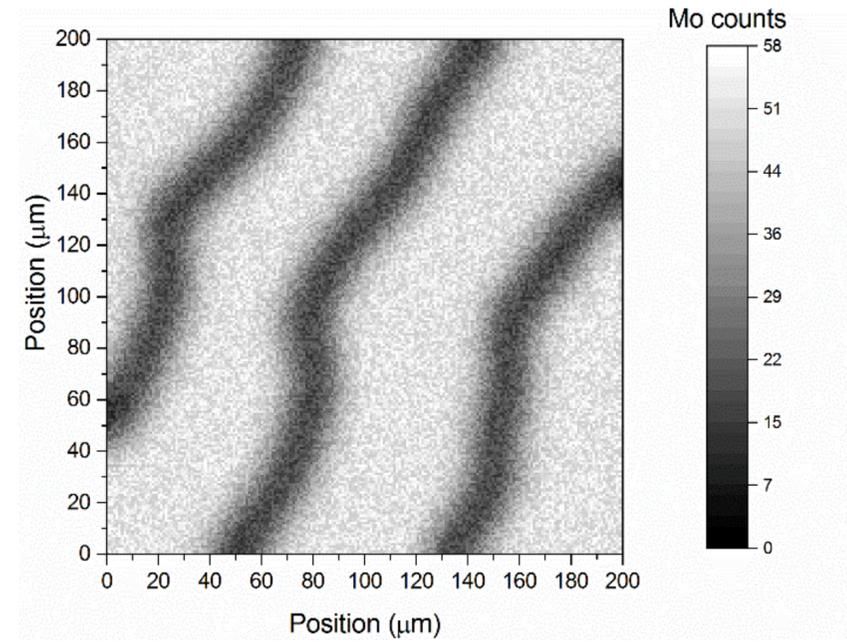
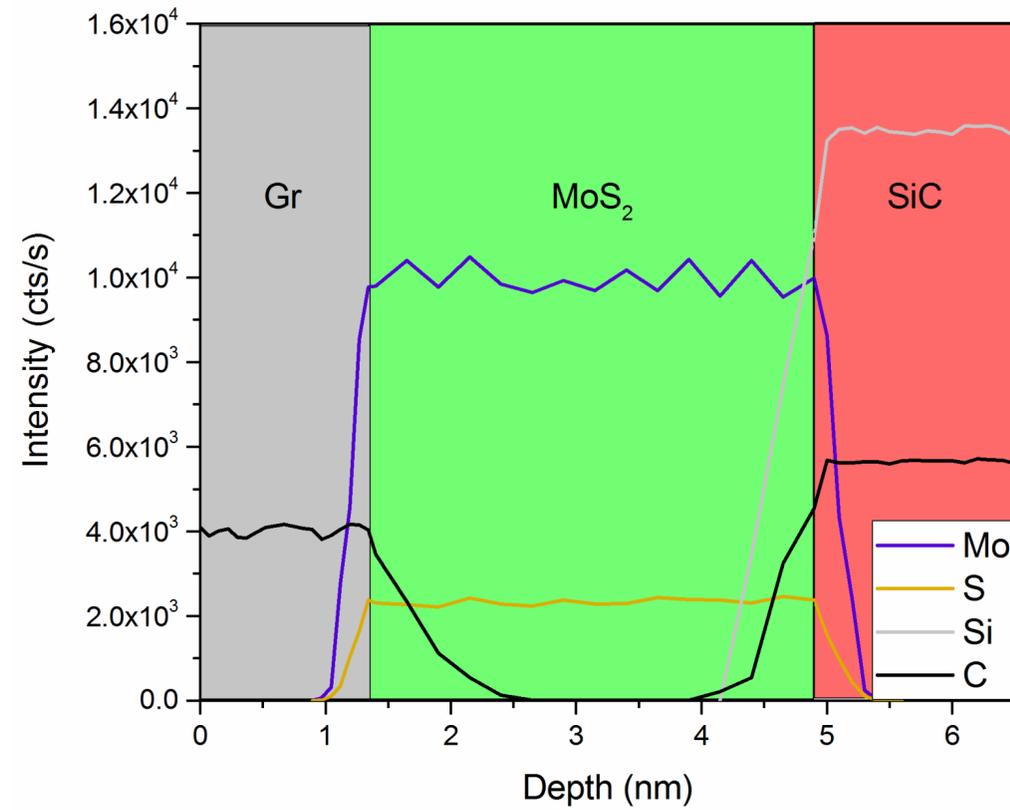
$\text{Al}_2\text{O}_3$



# Substrate type / procedure optimization



# Graphene/SiC case



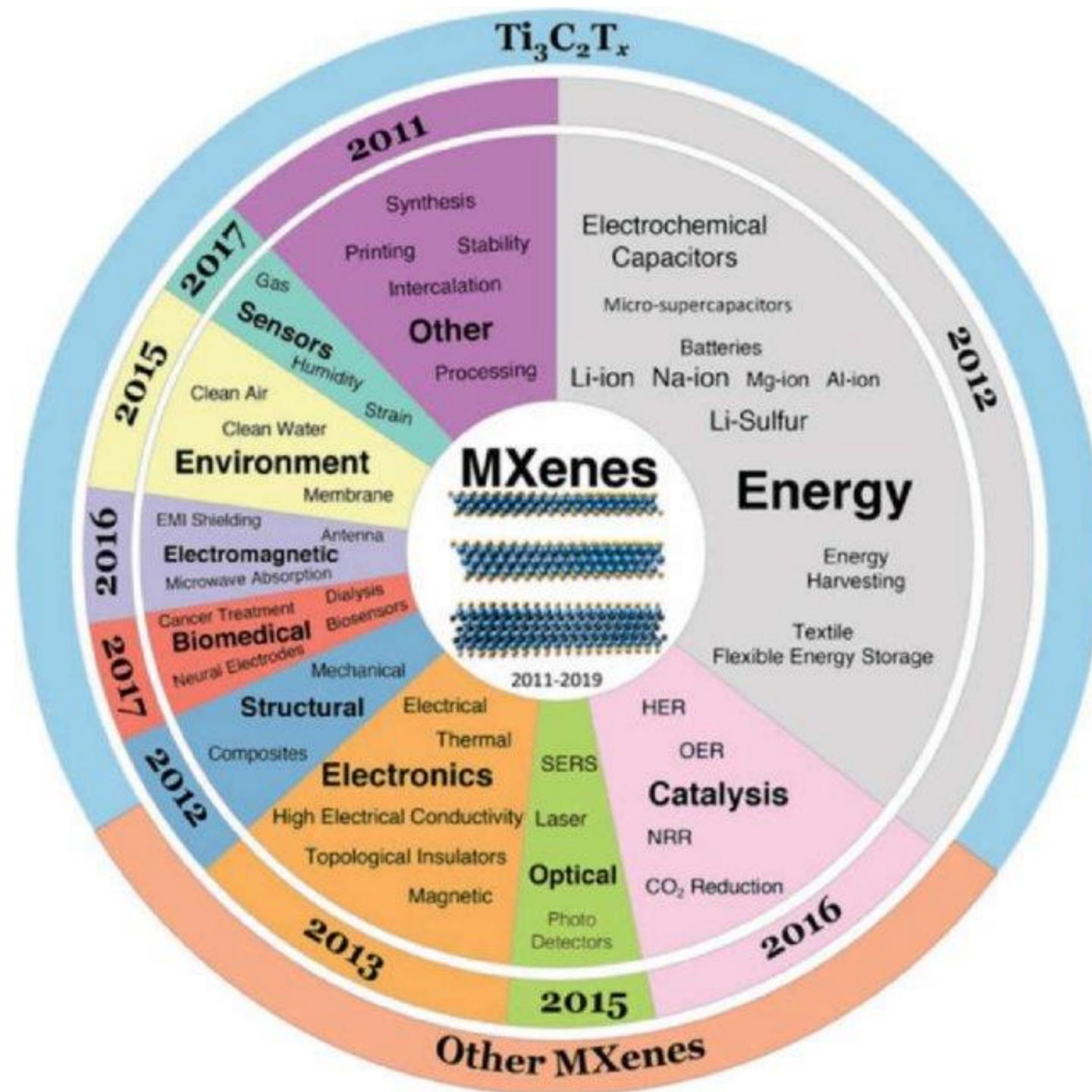
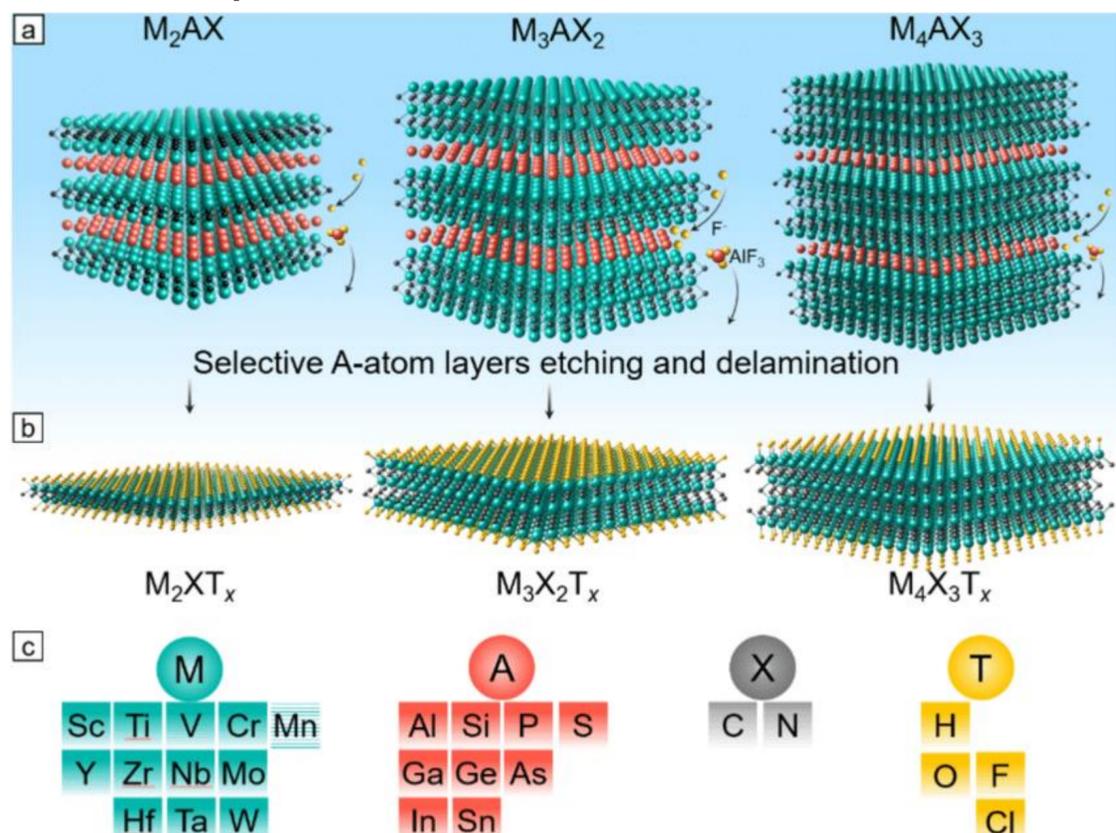
# MXenes

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- MXenes: a new family of two-dimensional (2D) transition metal carbides, carbonitrides and nitrides
- Synthesized from a MAX phase



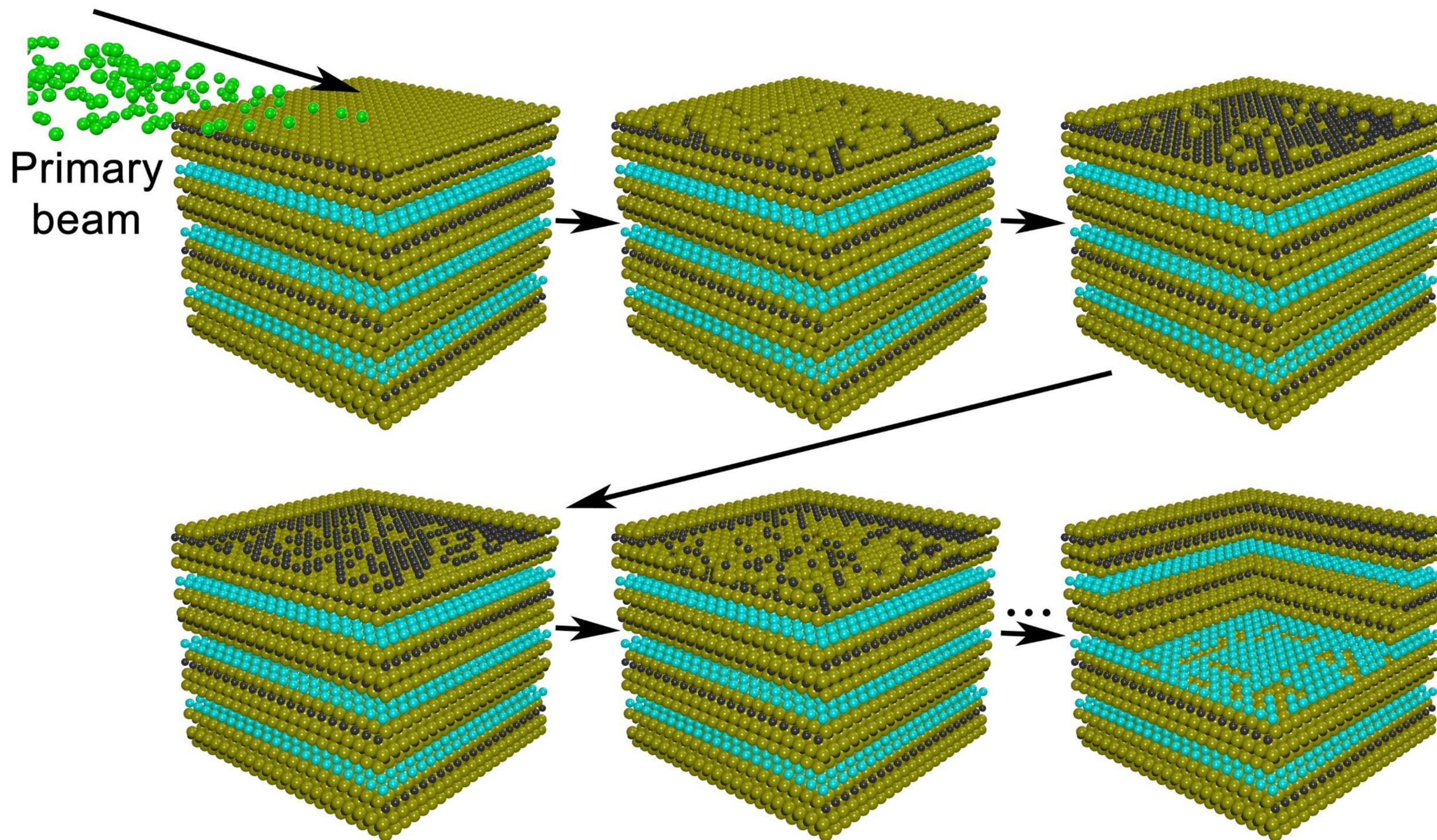
Prof. Yury Gogotsi



<https://nano.materials.drexel.edu/research/synthesis-of-nanomaterials/mxenes/>

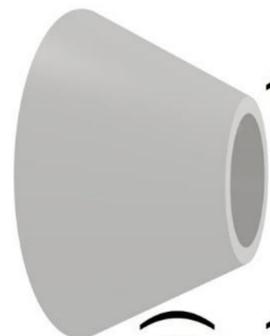
Hong, W. et al. *MRS Bulletin* **45**, 850–861 (2020).

# How to make such measurements?

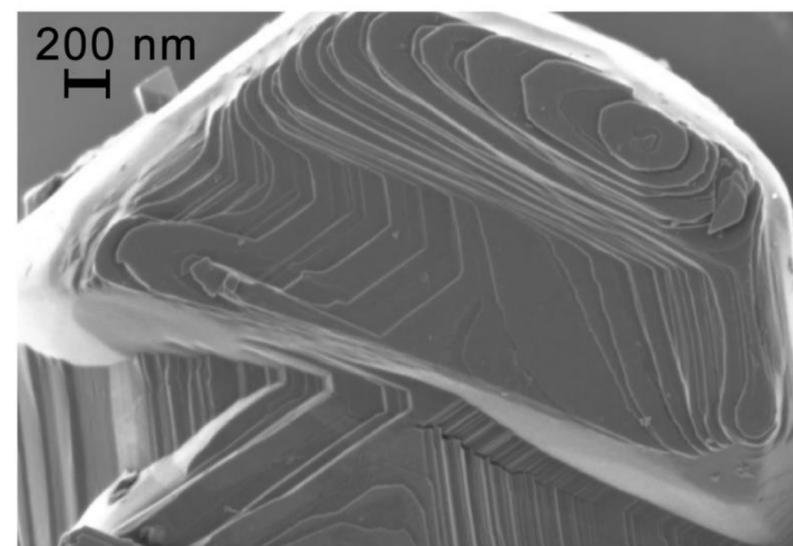
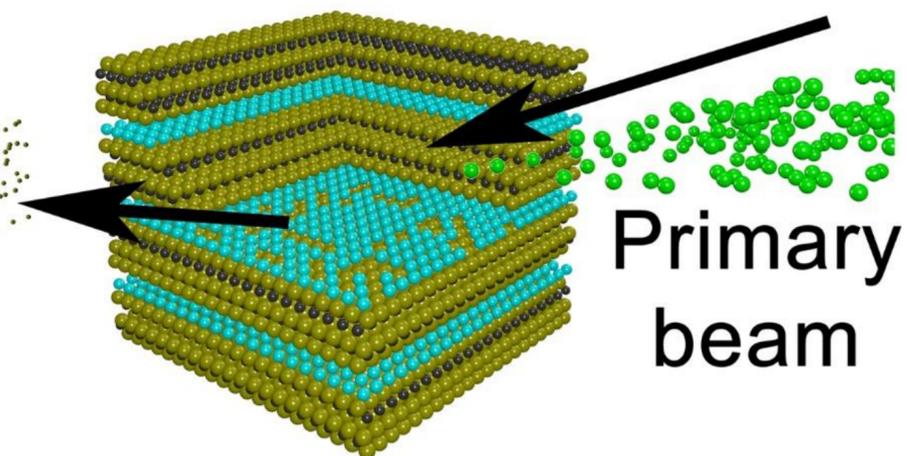
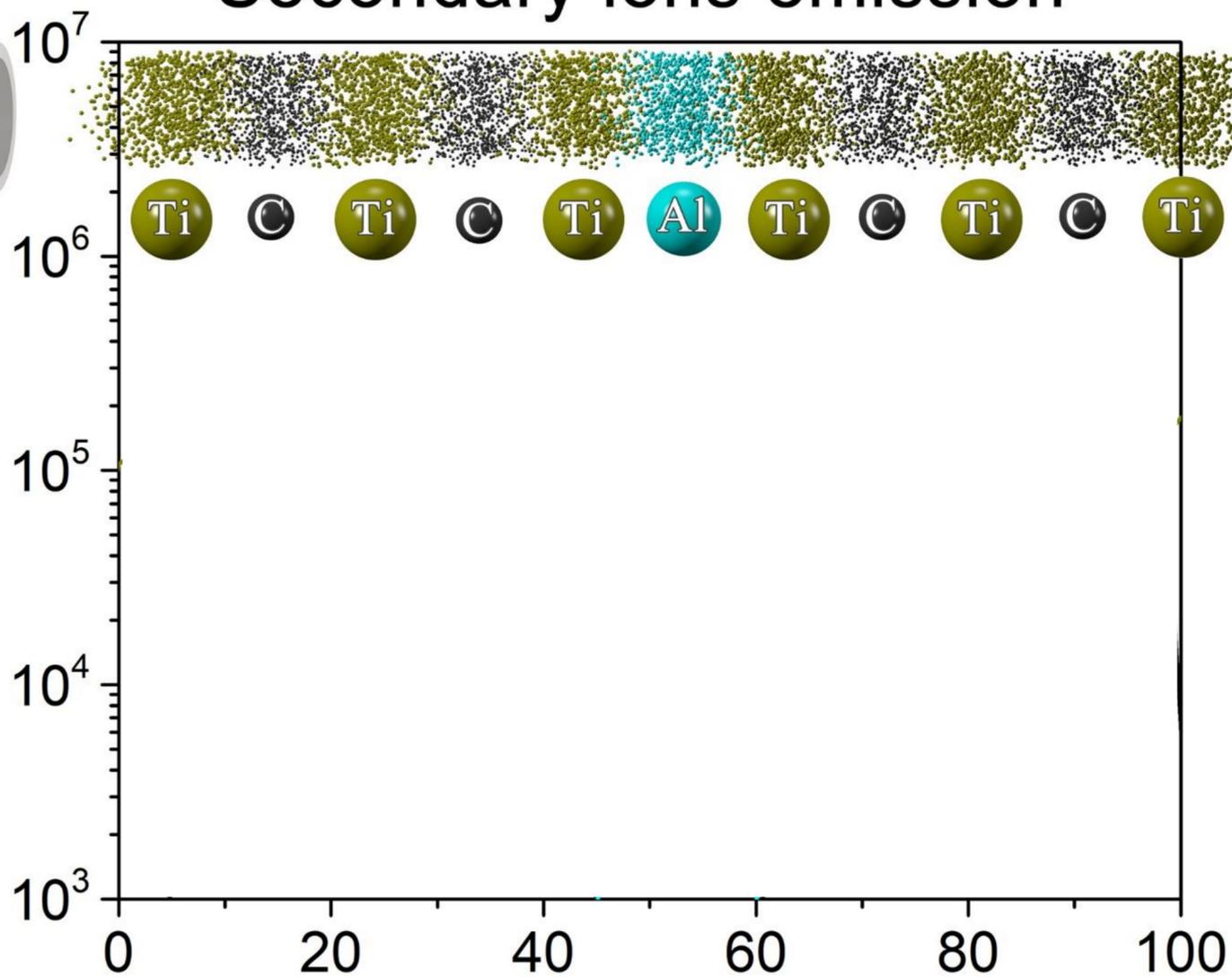


# A depth profile of $\text{Ti}_3\text{AlC}_2$ MAX phase

Detector

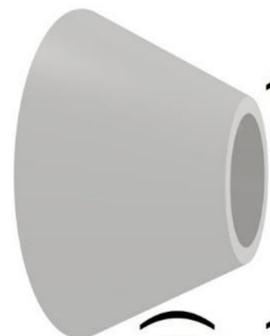


Intensity (cts)

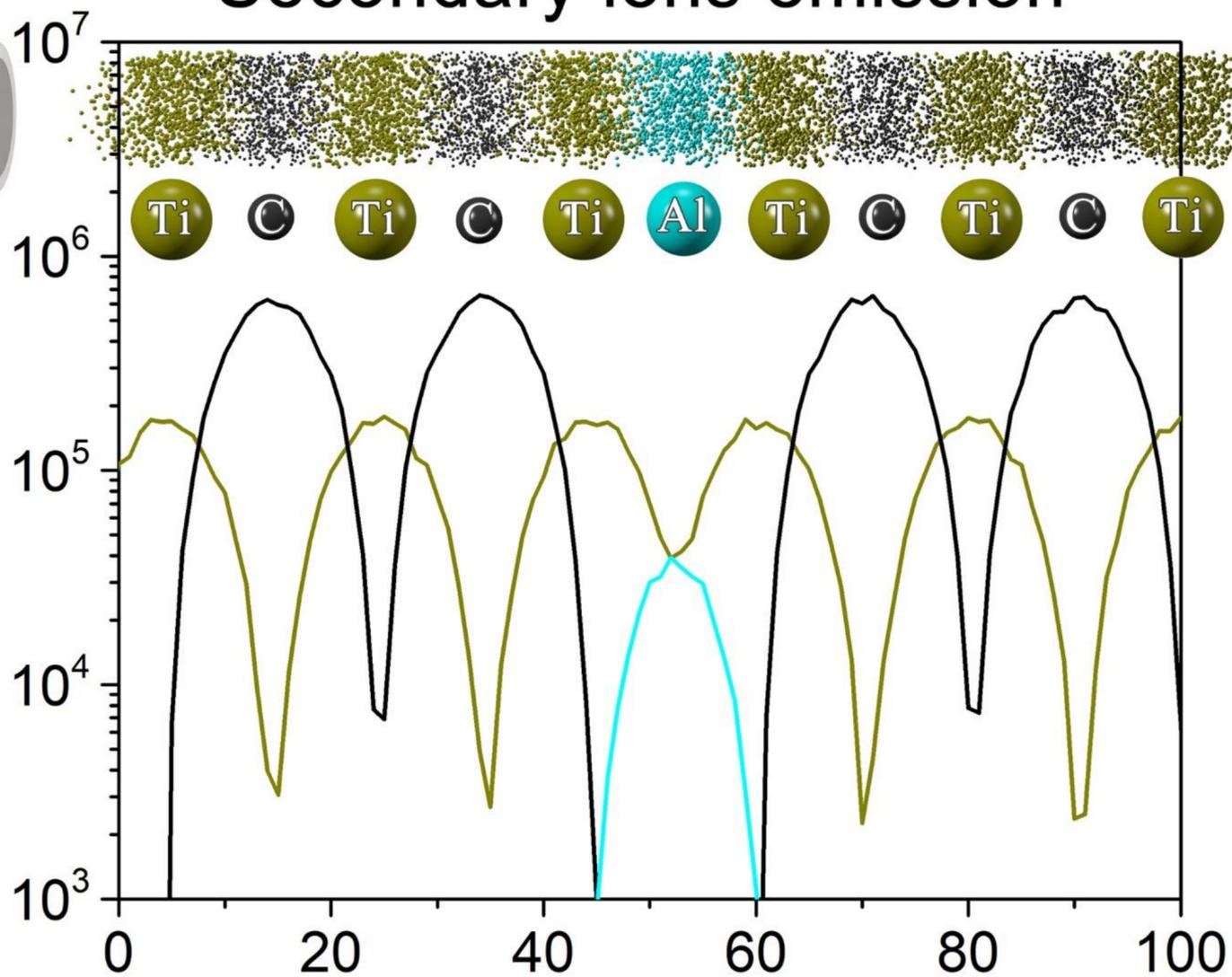


# A depth profile of $\text{Ti}_3\text{AlC}_2$ MAX phase

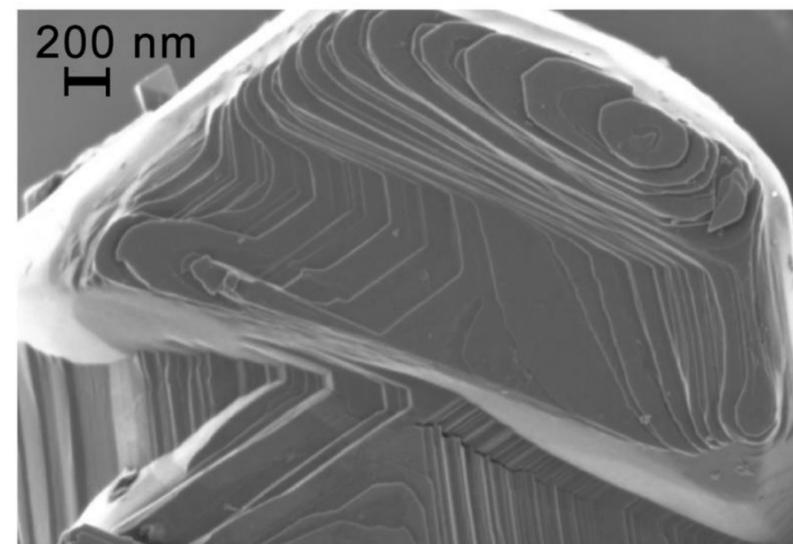
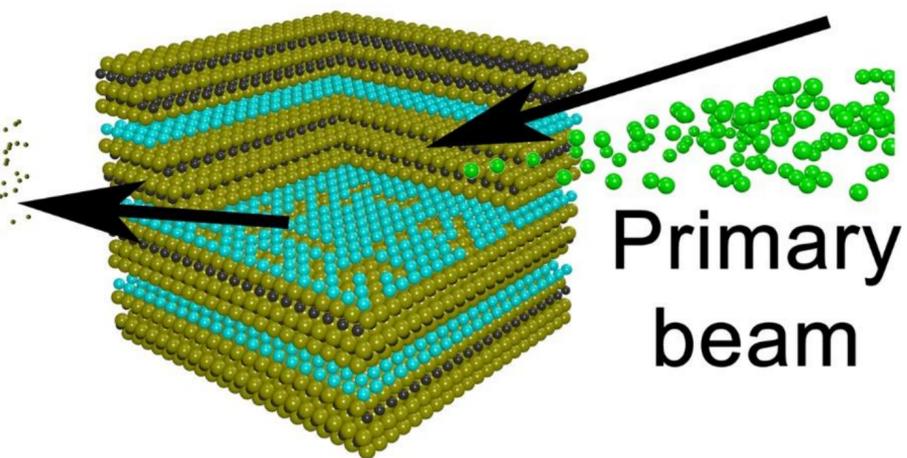
Detector



Intensity (cts)



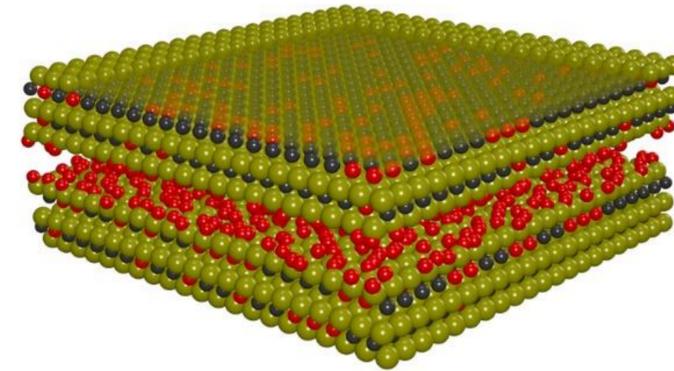
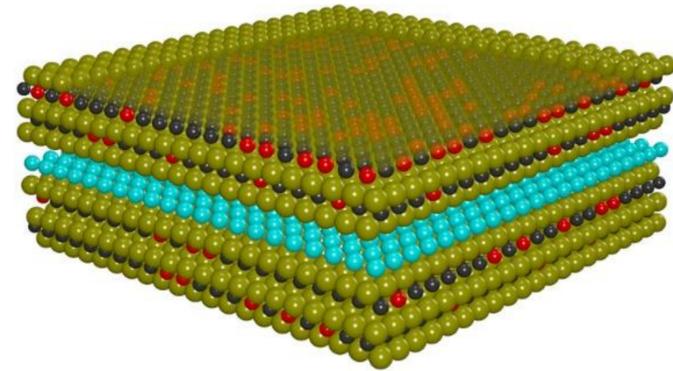
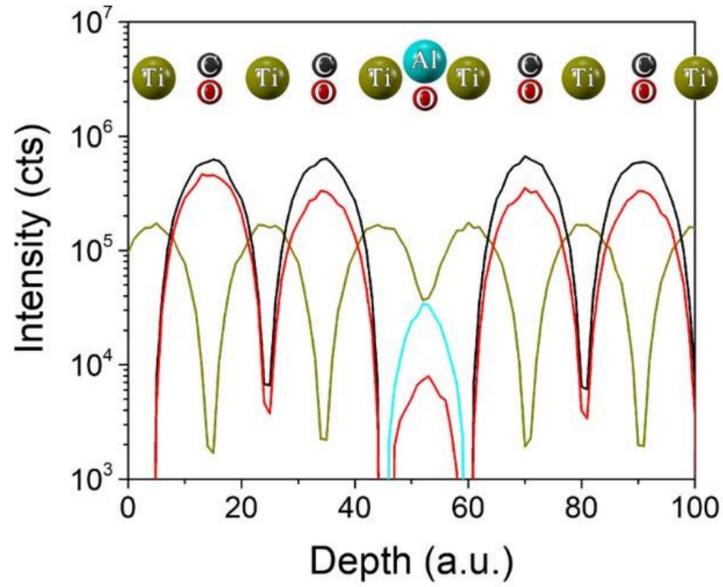
Depth (a.u.)





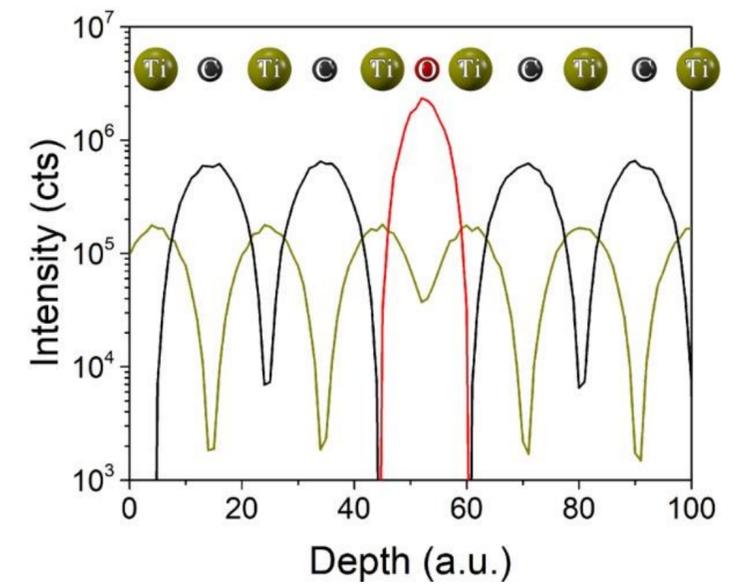
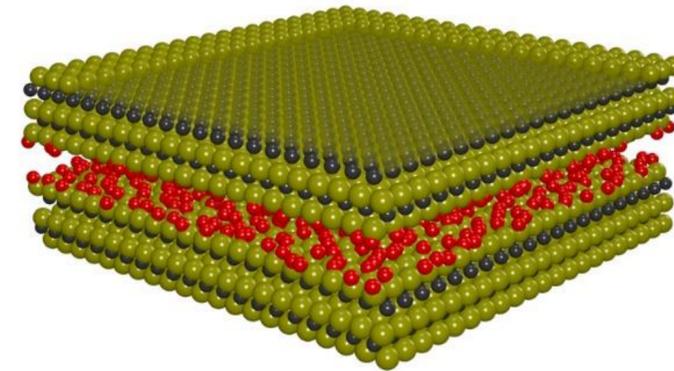
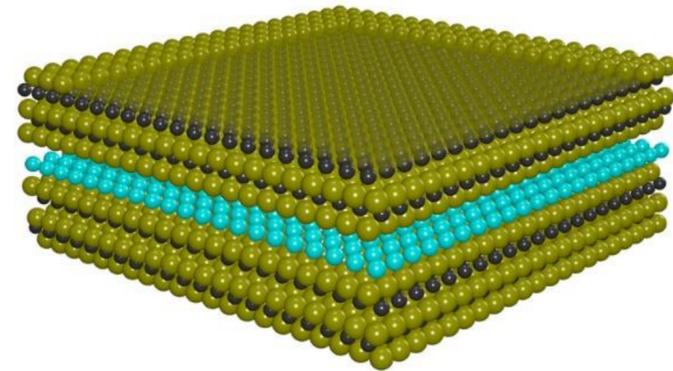
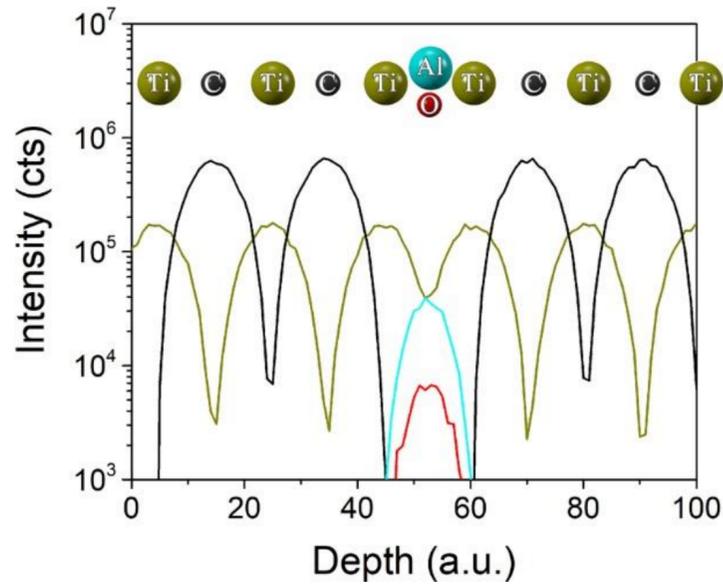
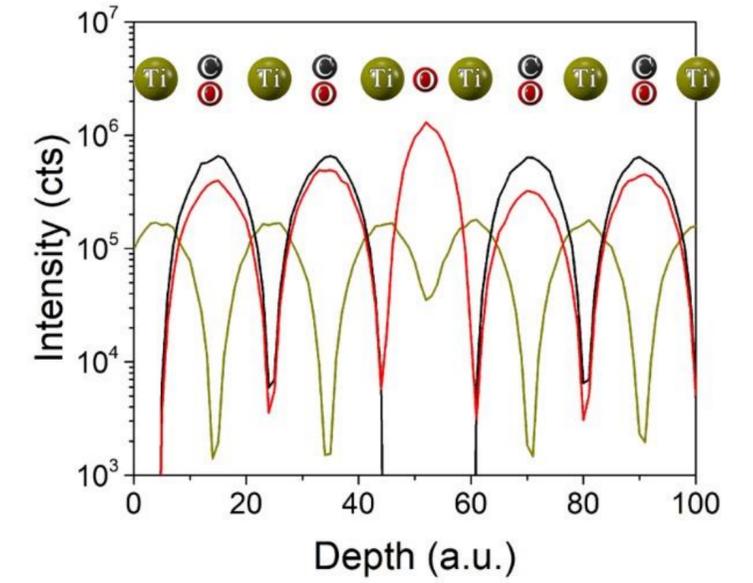
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# Carbides? Or oxycarbides?

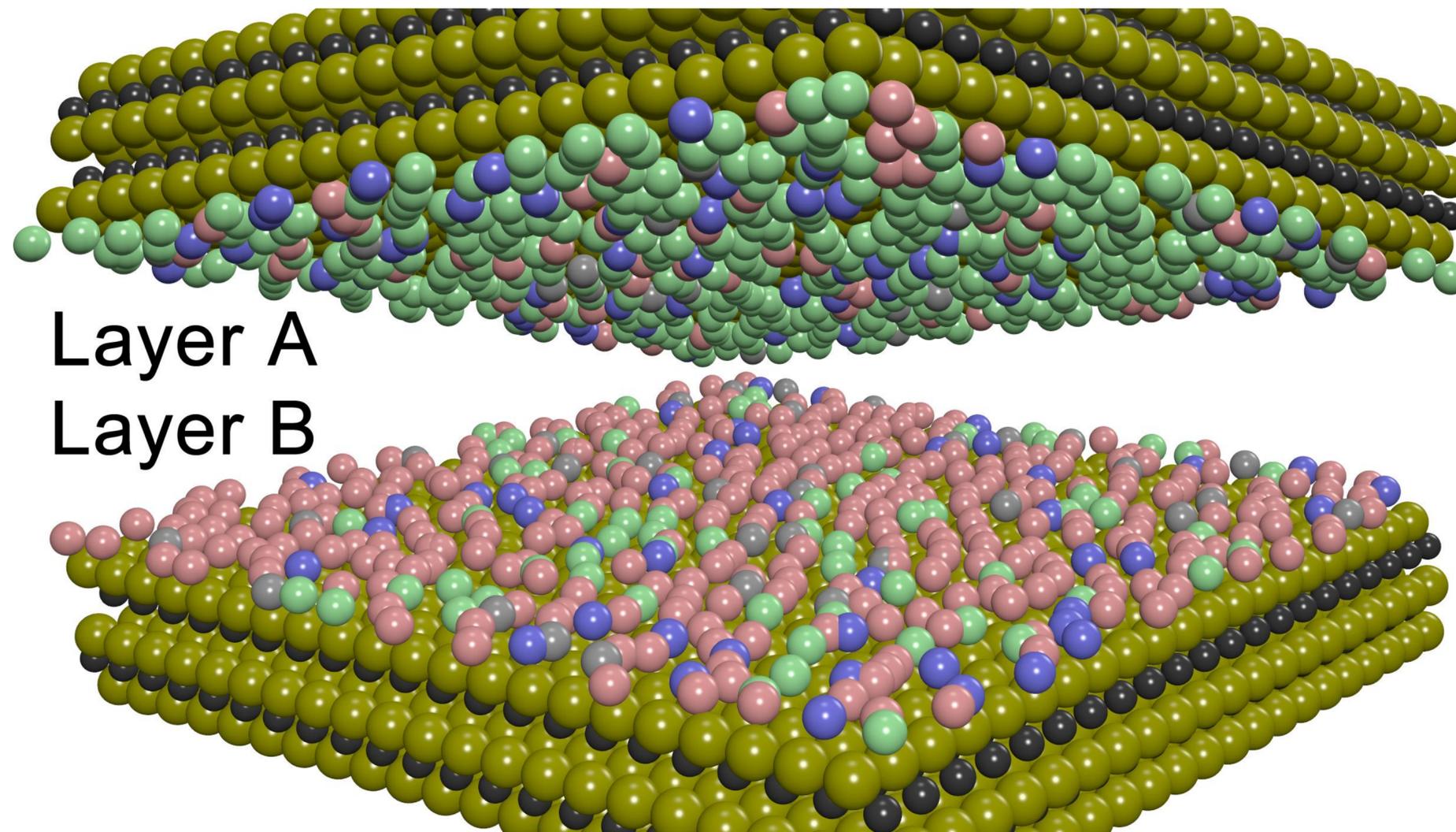
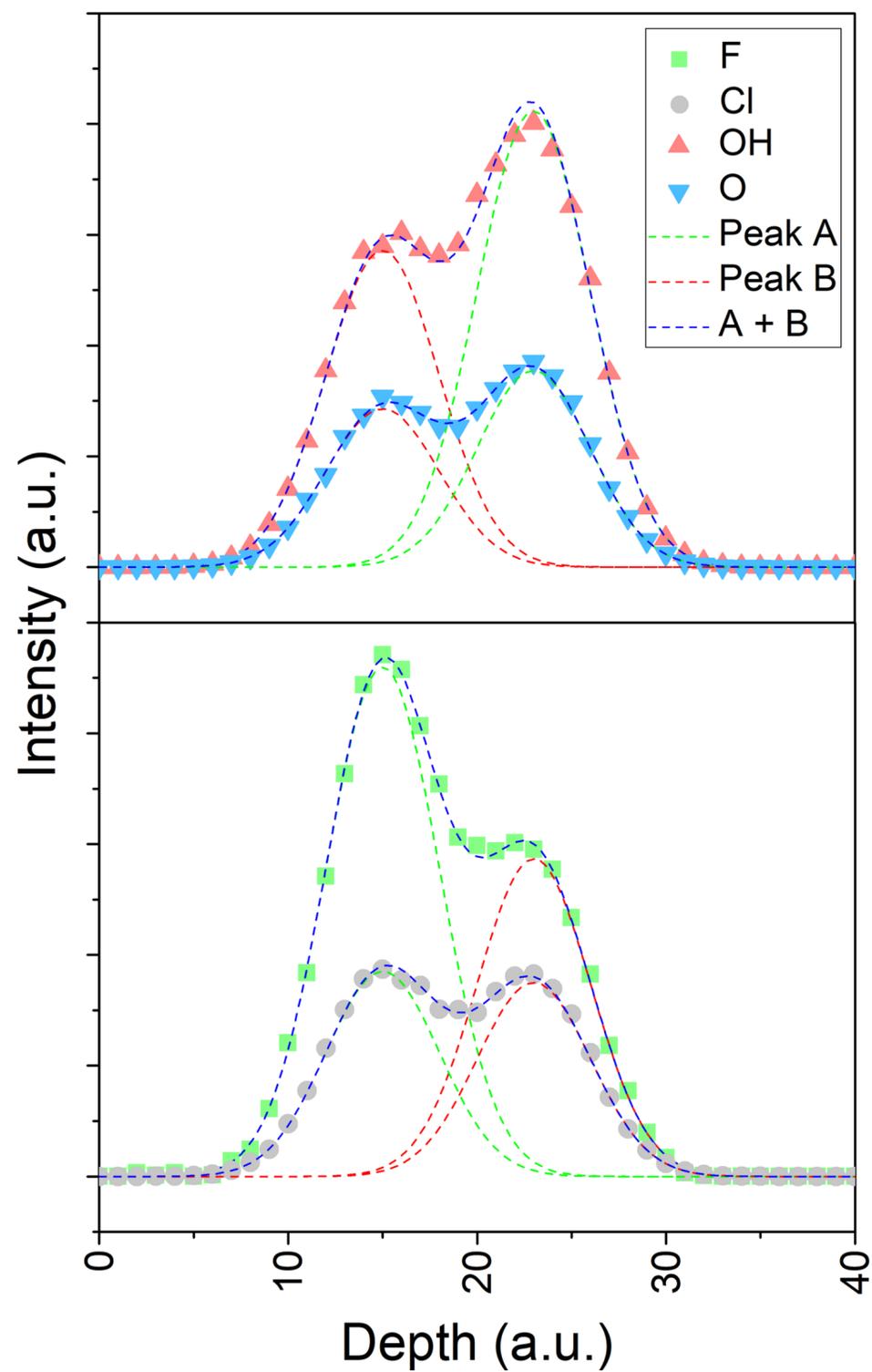


HF etching

MAX  $\longrightarrow$  MXene



# Termination layers





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## Conclusions

- State-of-the-art instrument
- Dedicated procedures (time-consuming but worth it!)
- Superior depth resolution (even atomic!)
- Only slightly worse detection limits

**SIMS can be used for 2D materials!**

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